

# The New High-Dynamics DCM for Sirius

On behalf of the Beamline Engineering Group of LNLS

September, 13<sup>th</sup> 2016

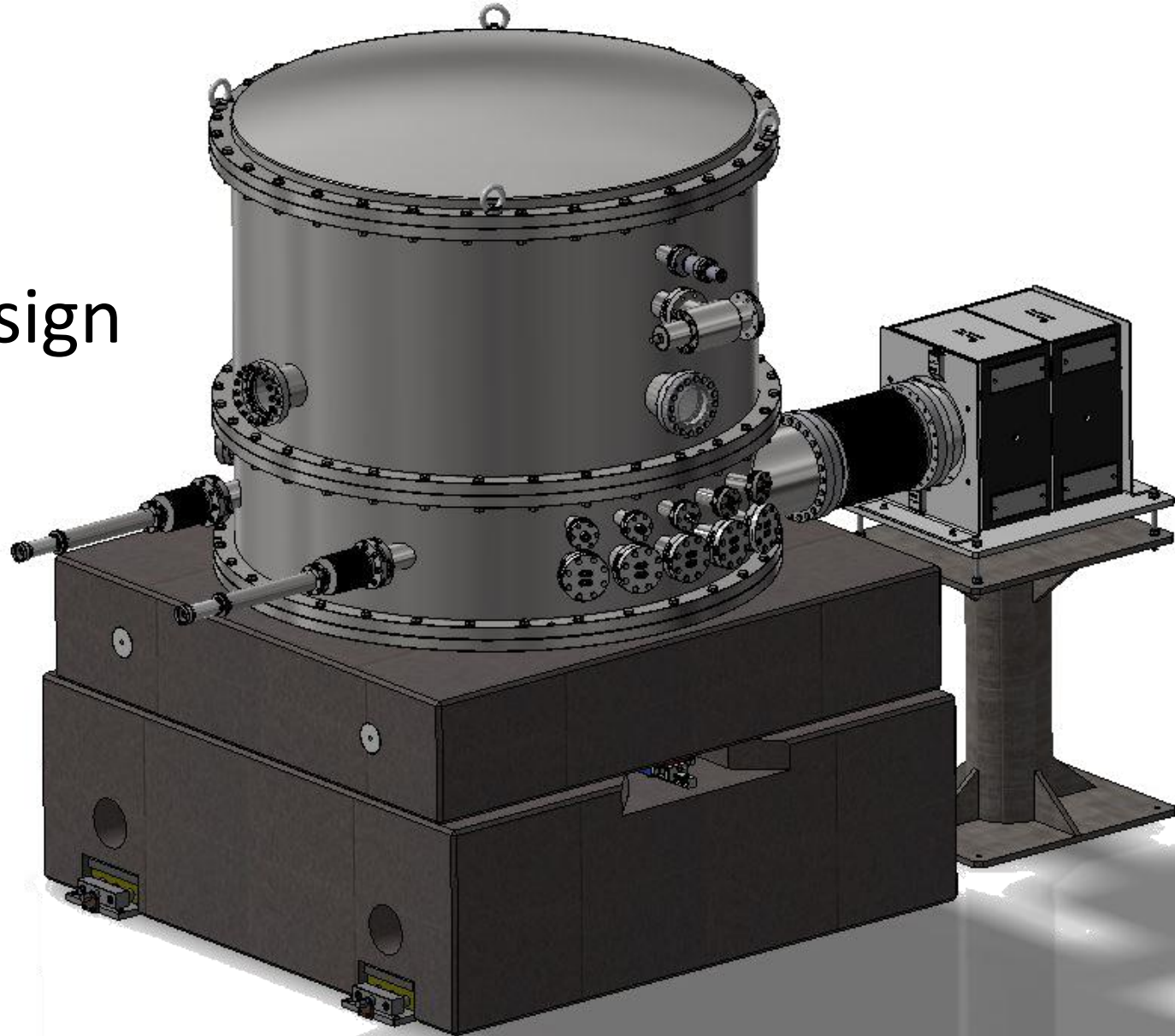
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MEDSI 2016

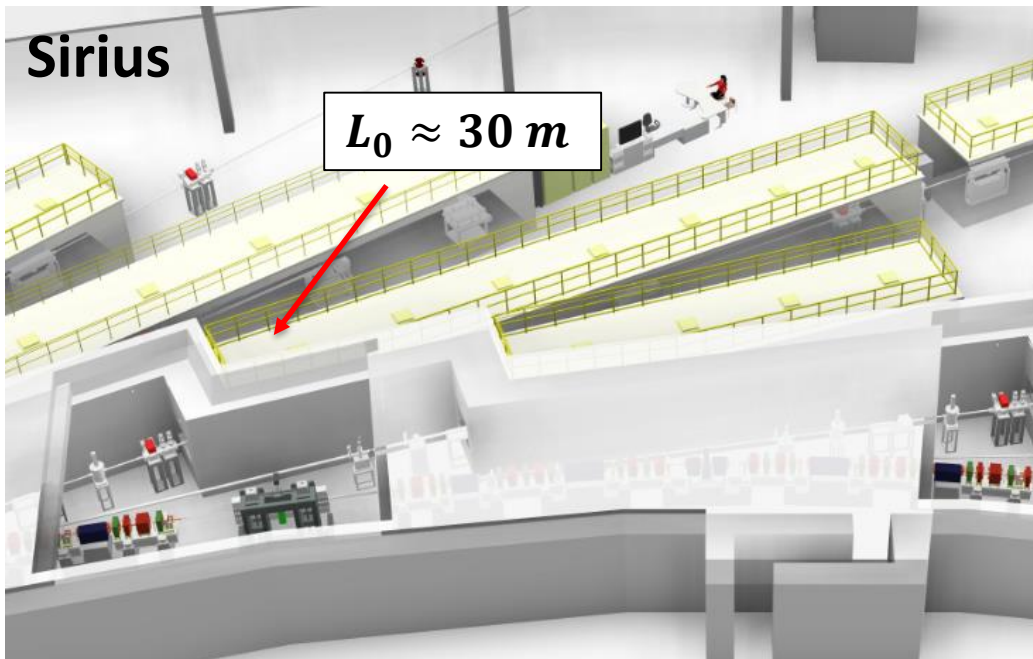
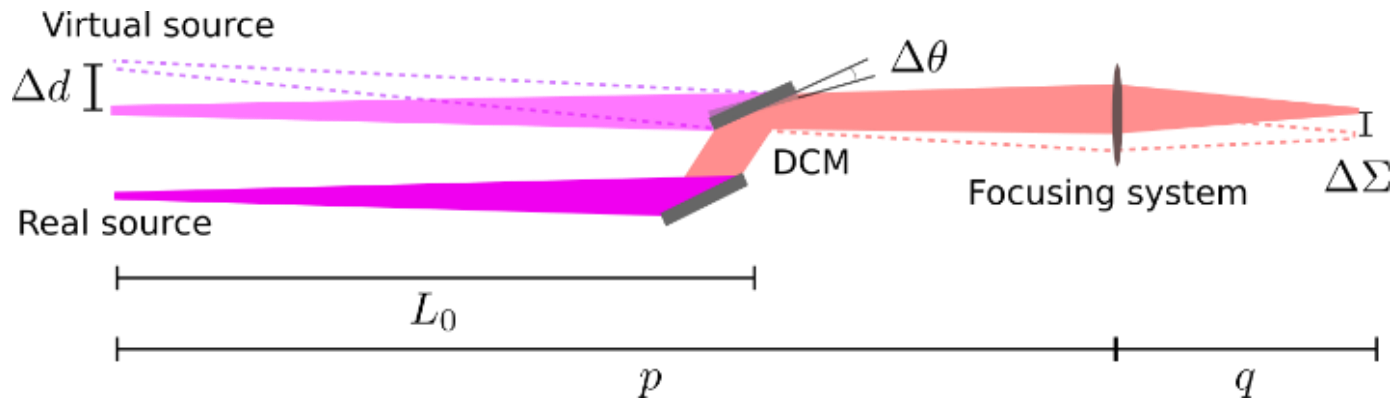
MECHANICAL ENGINEERING DESIGN OF SYNCHROTRON  
RADIATION EQUIPMENT AND INSTRUMENTATION

- Motivation
- Specifications
- Concepts
- Mechanical Design
- Conclusions

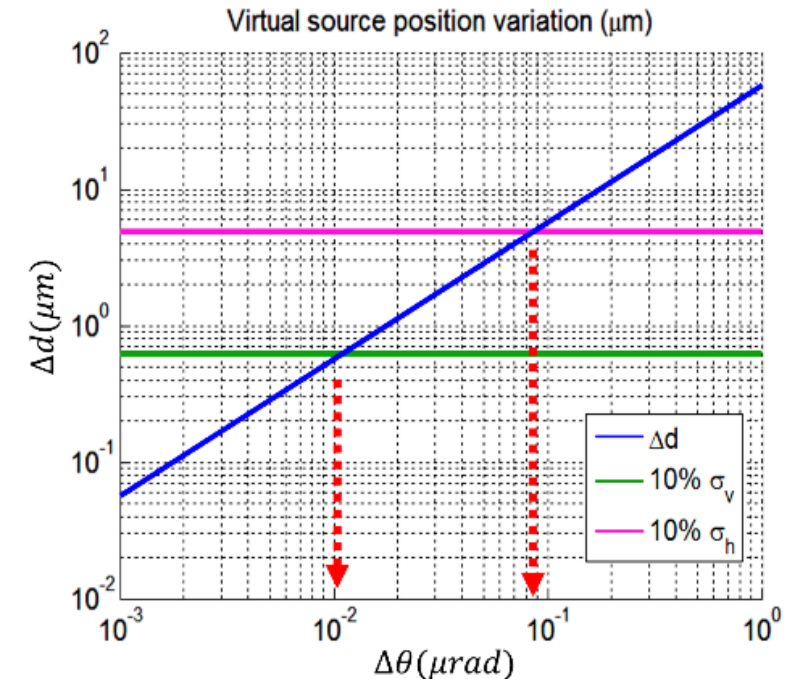




## DCM performances for the next generation machines



→  
 10%  
 source  
 size



# Specifications

Parameter	Description
Type:	Vertical DCM
Beam offset:	18 mm
Angular range:	3 to 60°
Angular resolution:	0.2 $\mu$ rad
Pitch/roll stability:	in-position: < <b>10 nrad</b> ( $\pm 3\sigma$ ) flyscan: 200 nrad ( $\pm 3\sigma$ )
Crystal sets:	Si(111): 2.3 to 38 keV Si(311): 4.4 to 72 keV
Crystal sizes (W x L):	1 <sup>st</sup> crystal: 15 x 35 mm <sup>2</sup> 2 <sup>nd</sup> crystal: 15 x 190 mm <sup>2</sup>
Crystal cooling:	1 <sup>st</sup> crystal: Indirect LN <sub>2</sub> (80 K) 2 <sup>nd</sup> crystal: Copper straps (155 K)
Crystal DoF:	1 <sup>st</sup> crystal: fixed at rotation center 2 <sup>nd</sup> crystal: gap, pitch, roll
Beam size:	1.7 x 1.7 mm <sup>2</sup>
Input Power:	150 W
Base pressure:	< 5 x 10 <sup>-8</sup> mbar

## Degrees of freedom

- **Problem:**  
complexity and instability
- **Solution:**  
Bragg, gap, pitch, roll

## Closed-loop control bandwidth

- **Problem:**  
limited control bandwidth
- **Solution:**  
low-stiffness actuators with reaction mass

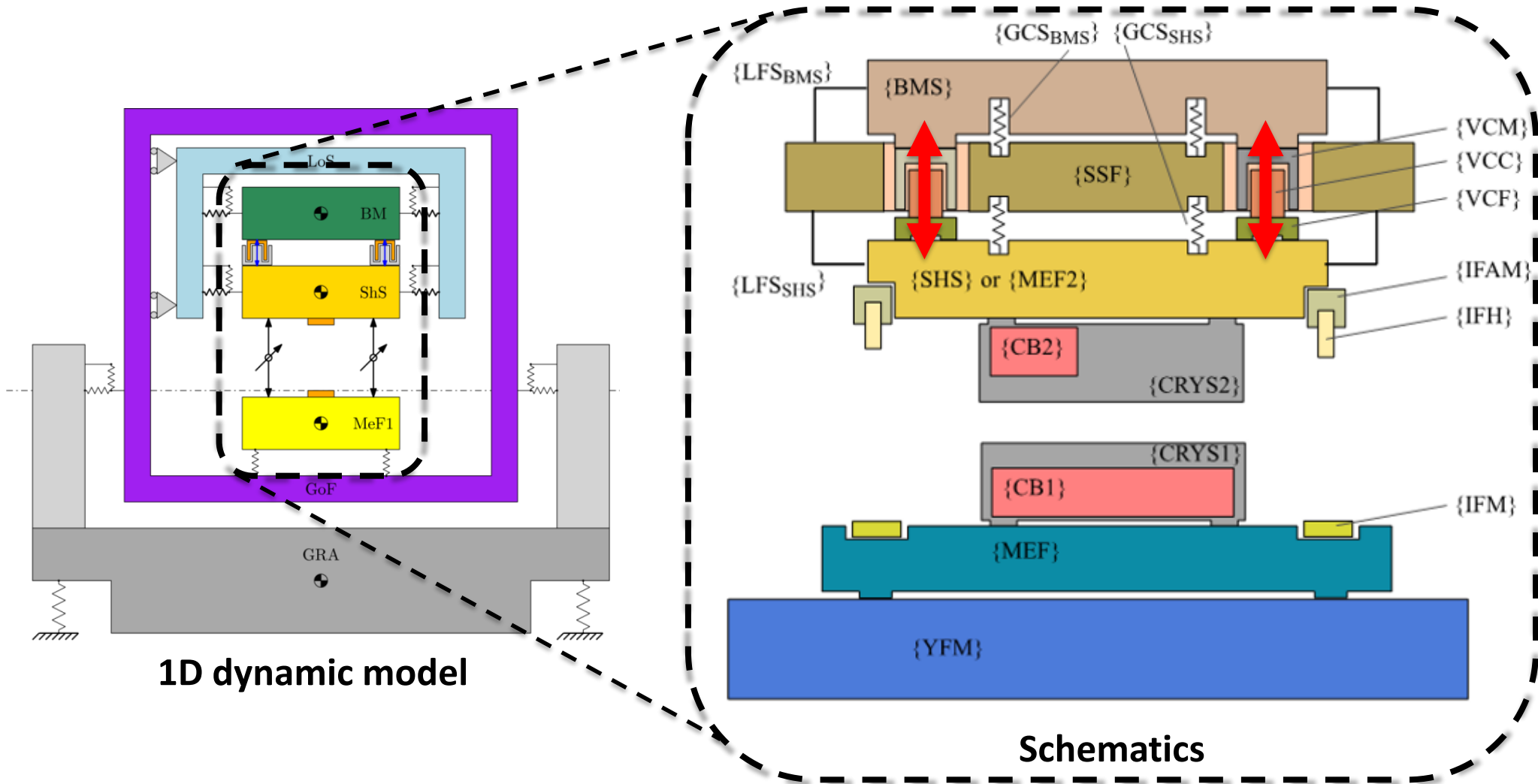
## Cooling disturbances

- **Problem:**  
flow vibrations
- **Solution:**  
tailored and balanced cooling channels

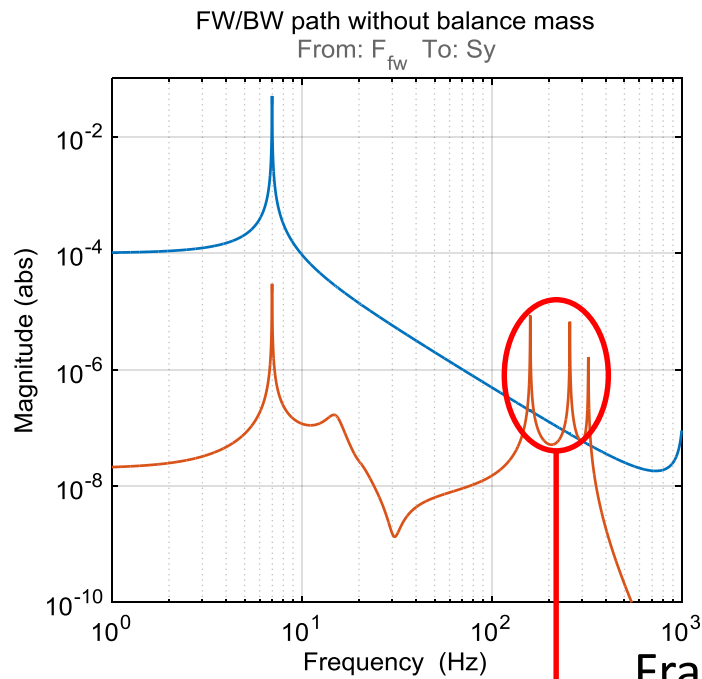
## Feedback

- **Problem:**  
sampling rate/precision/availability
- **Solution:**  
internal metrology

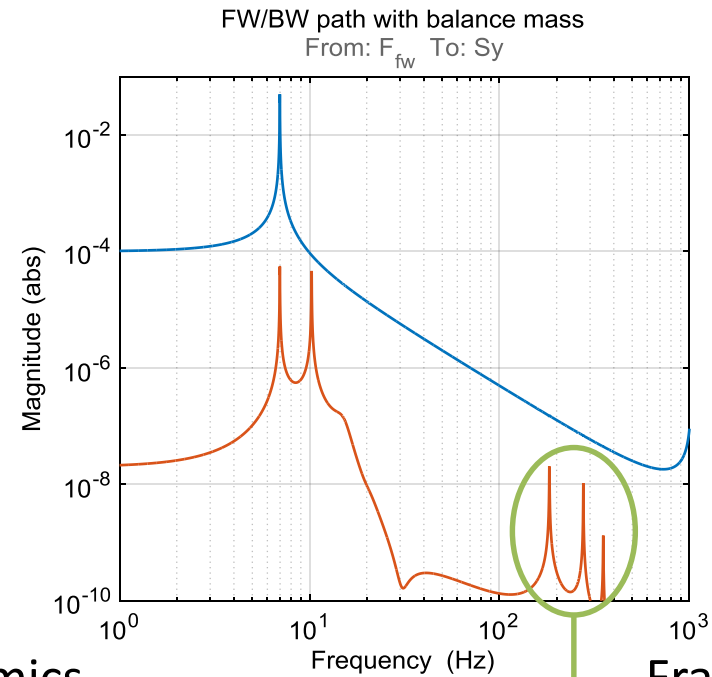
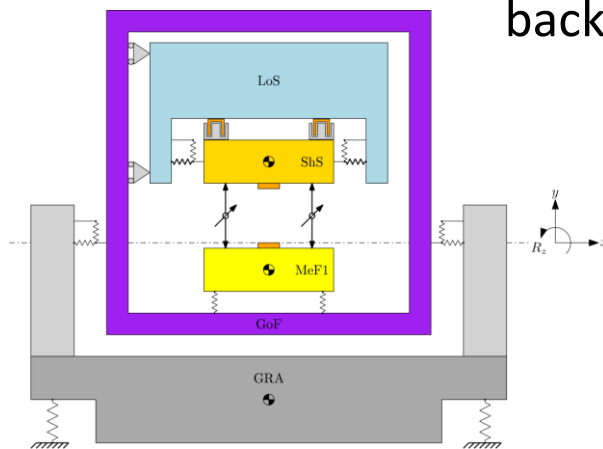
# Concept



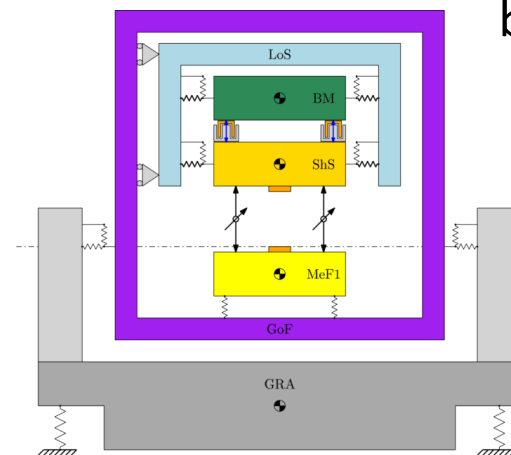
# Reaction Mass



Frame dynamics  
excited in  
backward-path.

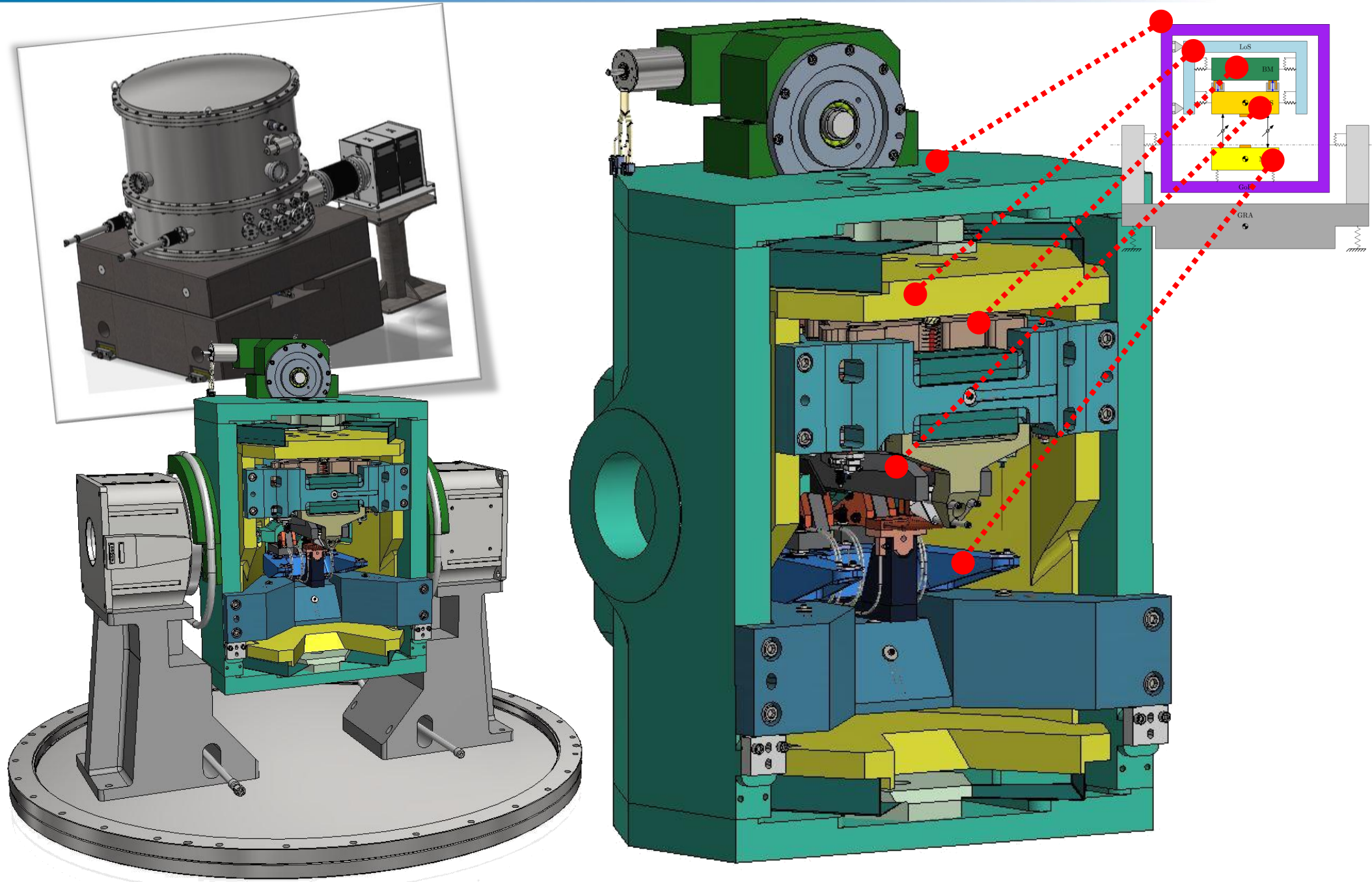


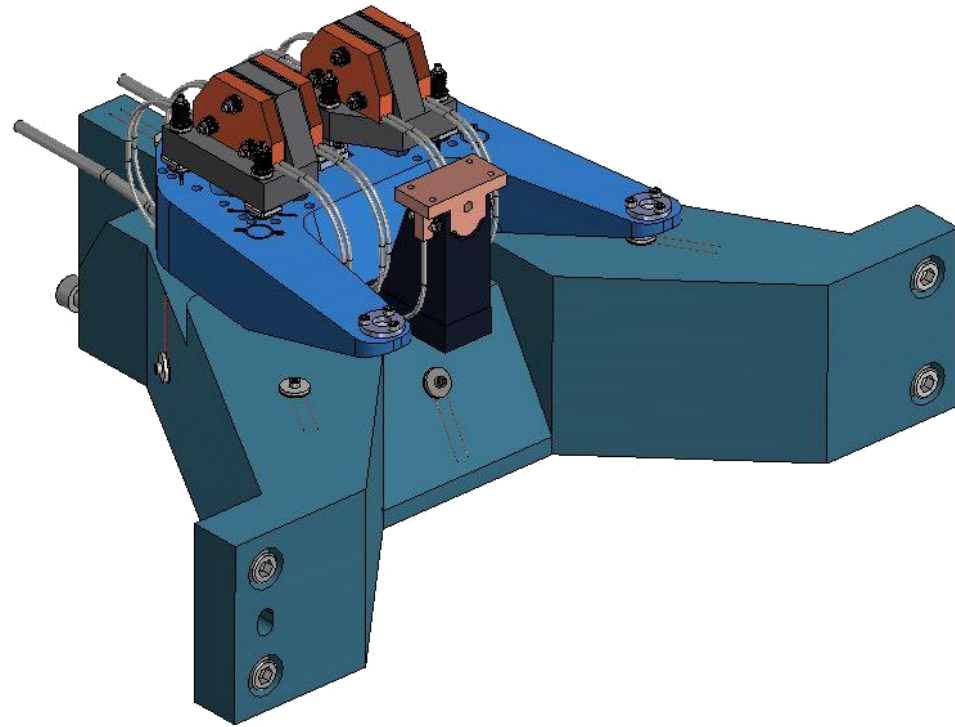
Frame dynamics  
excitation reduced  
by balance mass.



	<b>Lorenz (VC)</b> [nrad] ( $3\sigma$ )	<b>Piezo Stack</b> [nrad] ( $3\sigma$ )	<b>Piezo Walker</b> [nrad] ( $3\sigma$ )
Floor vibrations	0.8	2.5	0.9
LN <sub>2</sub> vibrations	?	?	?
Amplifier noise	1.4	44.1	2.9
Amplifier DAC quantization	0.2	0.2	0.2
DMI quantization errors	0.2	0.1	0.1
<b>Quadratic sum</b>	<b>1.6</b>	<b>44.1</b>	<b>3.1</b>
<b>Bandwidth (Hz)</b>	<b>200</b>	<b>20</b>	<b>20</b>
<b>Flyscan Compatibility</b>	<b>✓</b>	<b>×</b>	<b>×</b>



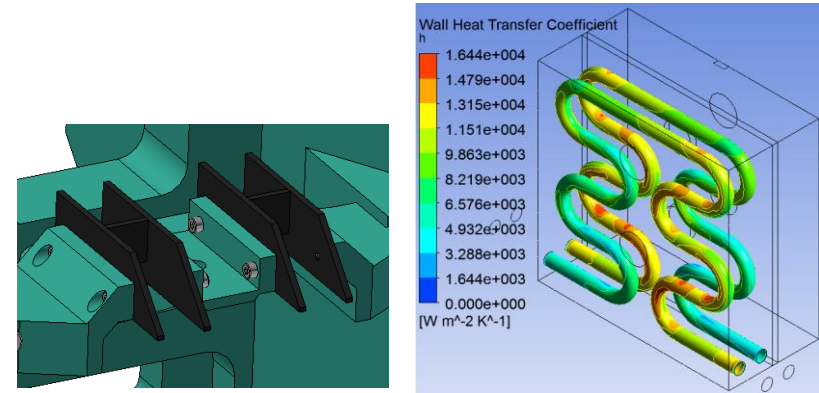




# Highlights

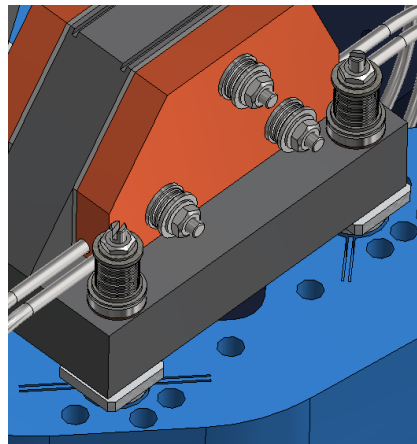
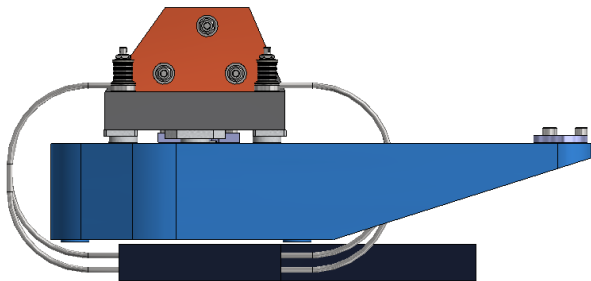
## Disturbances

- Cooling solutions for vibration reduction (and **measurements!**)
- Shielding “away” from crystals (GOF)



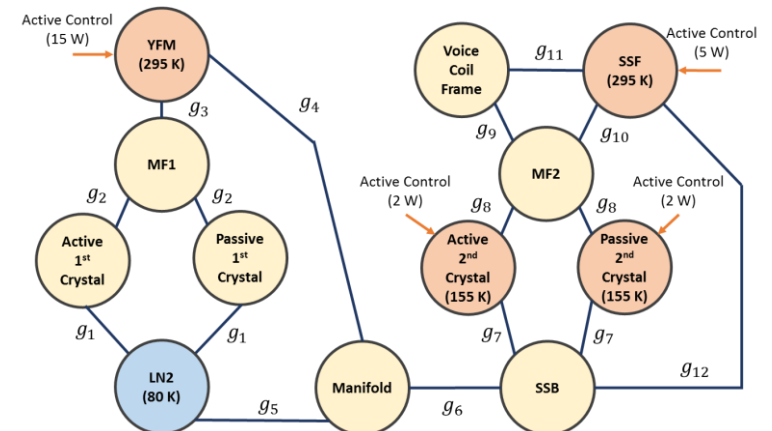
## Metrology

- Embedded metrology with nanometric performance
- Deterministic clamping for crystals
- Compliant cooling structures



## Thermal management

- Active thermal control



- All is running according to plan and a functioning prototype should be ready in mid-2017;
- The high-dynamics concepts are proven technology in the semiconducting industry and are now applied to this DCM.
- With 200 to 300 Hz servo bandwidth estimate, the stability target has been confidently pursued;
- Extensive mechanical, thermal, alignment and control analyses have been made in a predictive modelling approach.
- Concerning motion control and metrology for beamline instrumentation, this project has headed an unprecedented boost in competences and infrastructure at LNLS;
- These new engineering concepts have already started to be applied to projects of other opto-mechanical devices;
- Patent pending (INPI BR 10 2016 020900 5).

(Note: Dedicated posters about the mechatronics concept, flow-induced vibrations, thermal management and clamping complement this oral presentation.)

# Acknowledgements

The authors would like to gratefully thank:

- Brazilian Ministry of Science, Technology, Innovation and Communication;
- LNLS team;
- MI-Partners team;
- The community;
- The organizers;
- The audience.



## General

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## Control

	GOF	LOS	SHS	Therm.
<b>Actuator Type:</b>	Torque Motor	Servo	Voice-Coils	Foil Heaters
<b>Sensor Type:</b>	Rotary Encoder	Linear Encoder	FP IFM's	NTC RTD's
<b>Resolution:</b>	<50 nrad	<0.1 $\mu$ m	< 0.5 nm/ 5 nrad	<10 mK
<b>Closed-Loop BW:</b>	35 Hz	20 Hz	200 to 300 Hz	0.1 Hz
<b>Feedback Sampling:</b>	10 kHz	10 kHz	10 kHz	20 Hz